

"RESPONSE UNDER 37 CFR 1.116-EXPEDITED PROCEDURE EXAMINING GROUP 1763.

## IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

SHUEI SEKIZAWA, ET AL.

: EXAMINER: KACKAR

SERIAL NO: 09/840,178

FILED: APRIL 24, 2001

: GROUP ART UNIT: 1763

FOR: WORKTABLE DEVICE AND PLASMA PROCESSING APPARATUS FOR SEMICONDUCTOR PROCESS

## AMENDMENT UNDER 37 CFR §1.116

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated June 18, 2003, please amend the aboveidentified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.

Please enter Pk 10-8-03